

SOLID STATE PROTEIN SENSOR





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Why is it important?

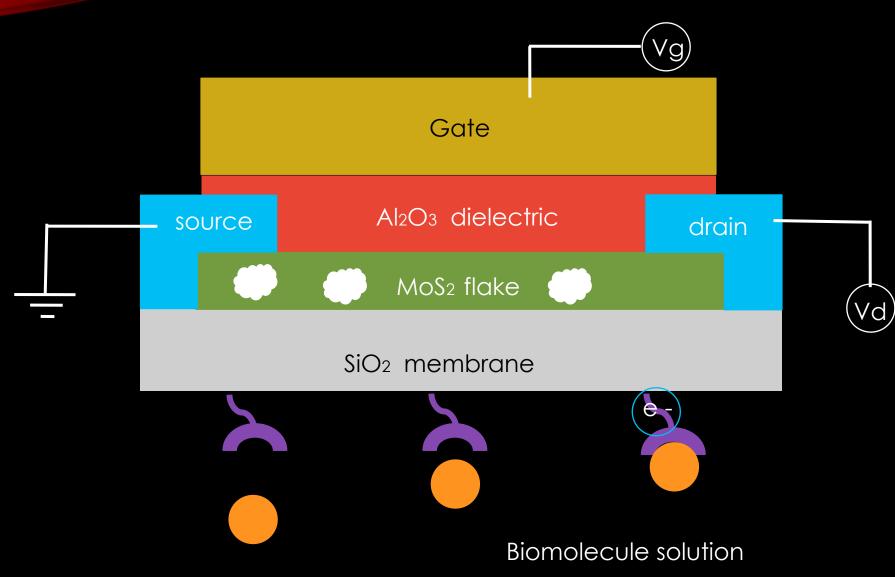
Personalized medicine

- Disease Identification
- Treatment (effects of pharmaceuticals)
- Identification of Neurotransmitter

What is a solid state protein sensor ?

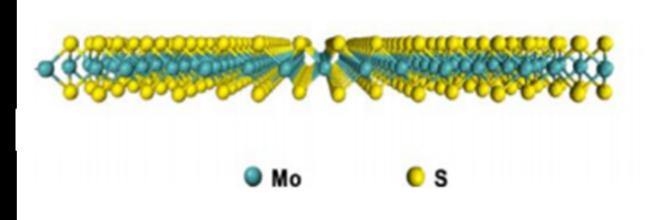
• A device that is used to detect the presence of specific atoms, molecules and ions in liquids by changing the amount of current.

How does it work?



Why use MoS₂?

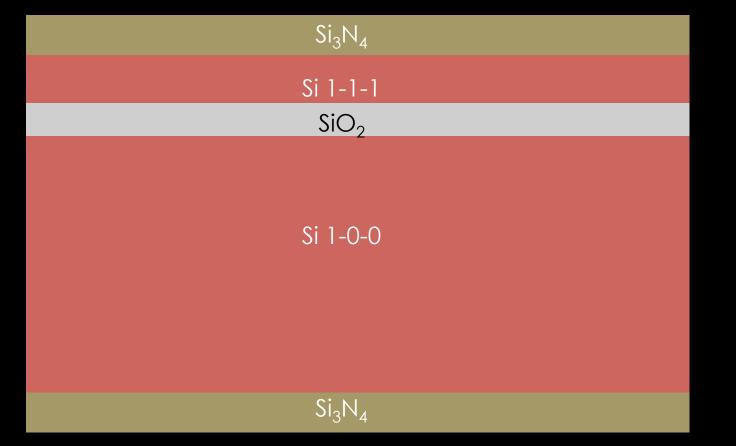
MoS₂



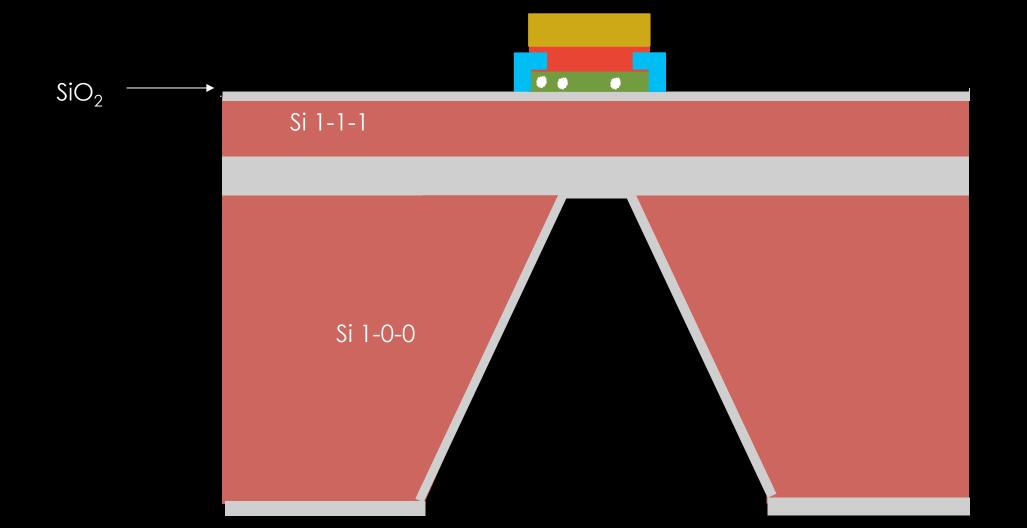
Energy Band Gap: 1.2-1.8 eV

Construction of target substrate out of a silicon-on-insulator (SOI)

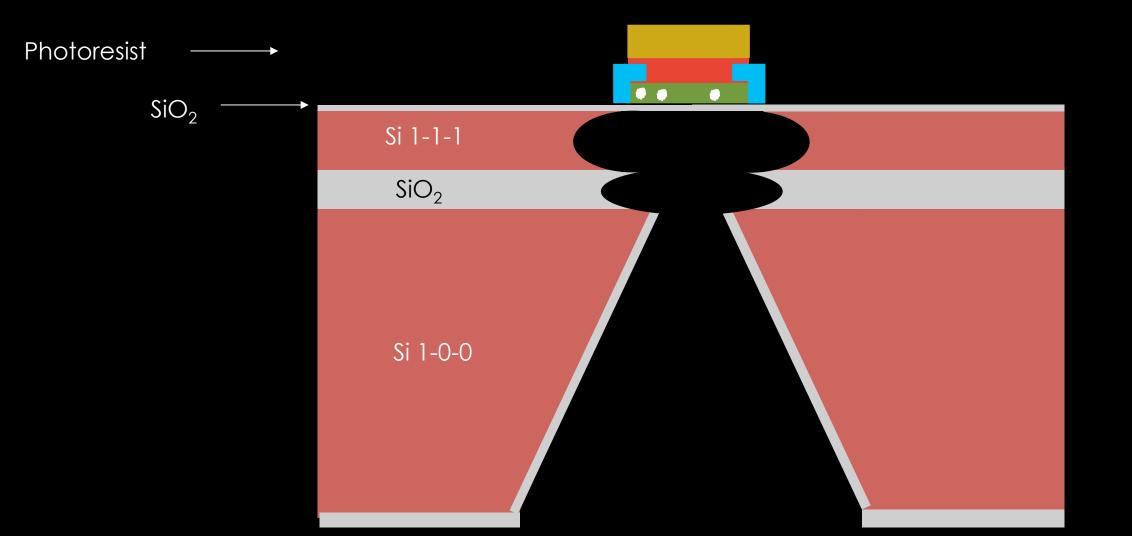
wafer



Etch, oxidize & place device on membrane



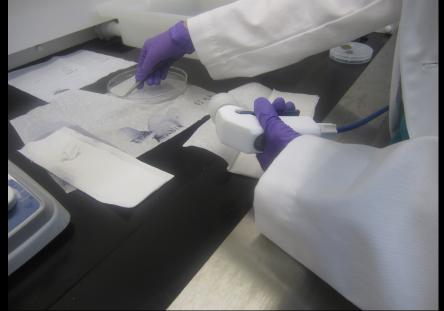
Etched and oxidized



Exfoliate MoS₂ flakes



Cleaning the dummy and target substrates



Acetone 70 C 30 mins.

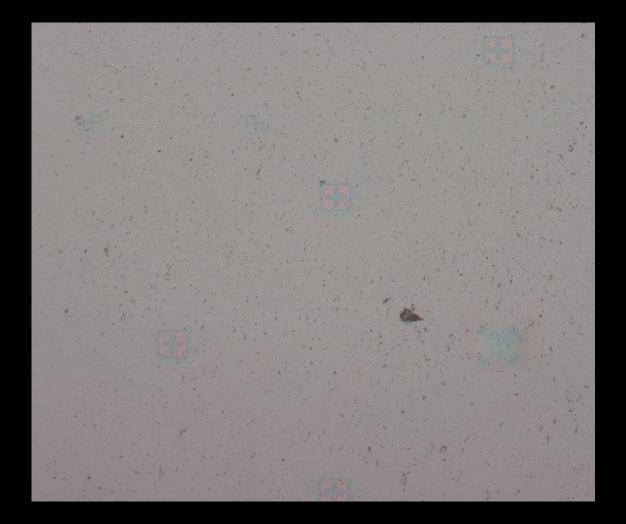
Isopropyl Alcohol Room temp 5 mins.



De-ionized Water Room temp 1 min.

Blow dry with nitrogen gas gun

Before and after cleaning



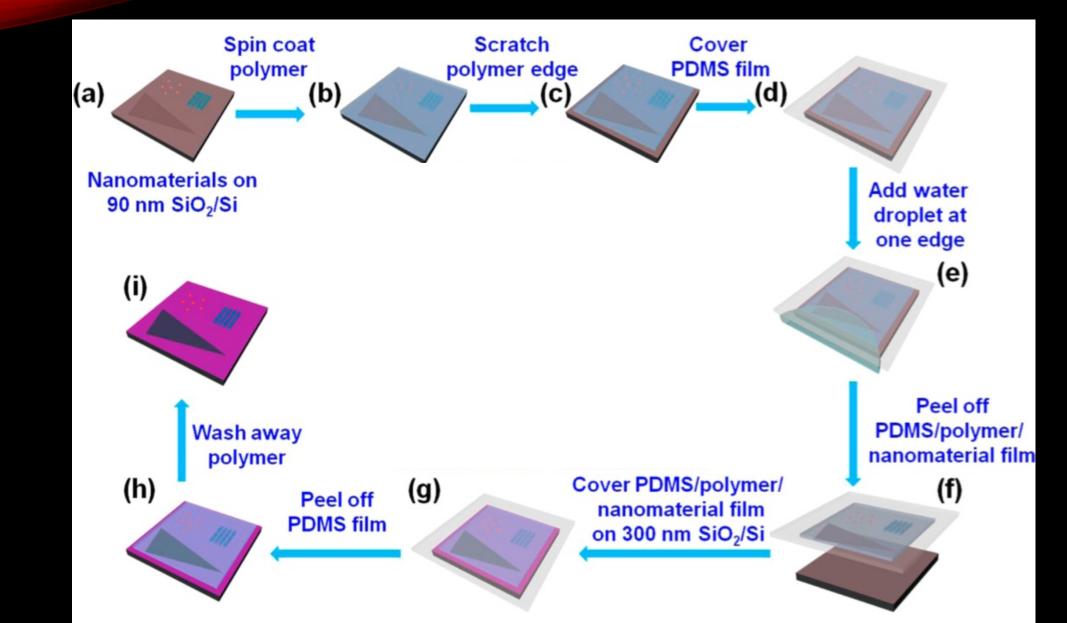


Deposit MoS₂ flakes onto dummy substrate





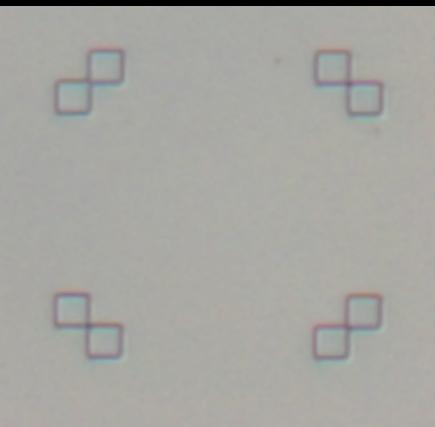
Transfer process



Hai Li, Jumiati Wu, Xiao Huang, Zongyou Yin, Juqing Liu, and Hua Zhang, 2014. ACS Nano, J. 8, 6564.

Transfer of MoS₂ flakes from dummy onto target





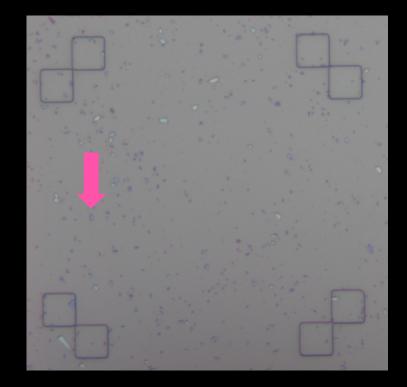
Criteria for desired flakes

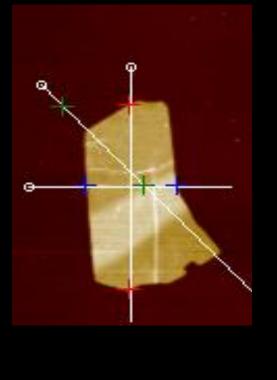
- $2-10 \,\mu\text{m}$ in length and width
- Roughly rectangular shape
- 10 20 nm thick
- Relatively flat surface

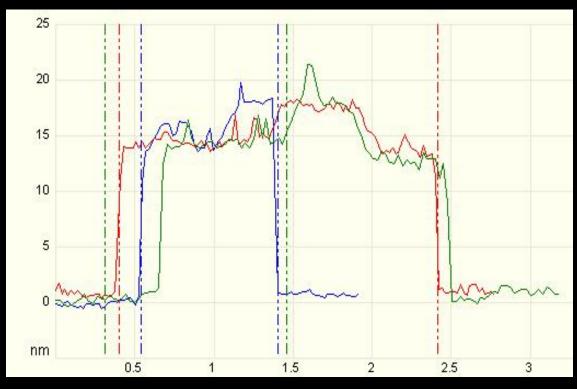
Optical microscopy (OM)

Atomic force microscopy (AFM)

A rejected MoS₂ flake

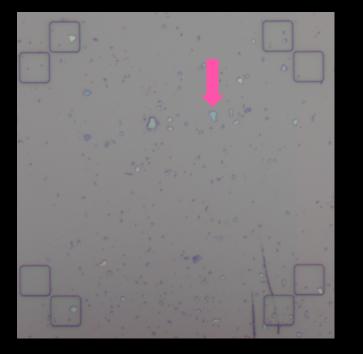


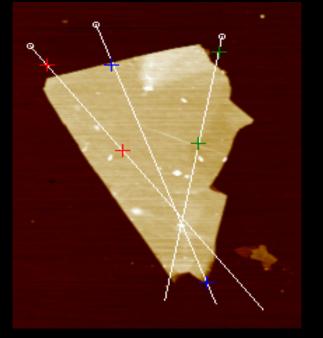


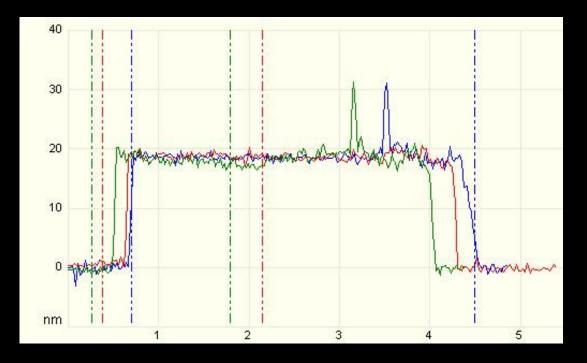


Length: ~0.861 µm Width: ~2.016 µm Average Thickness: 15.020 nm

A candidate MoS₂ flake

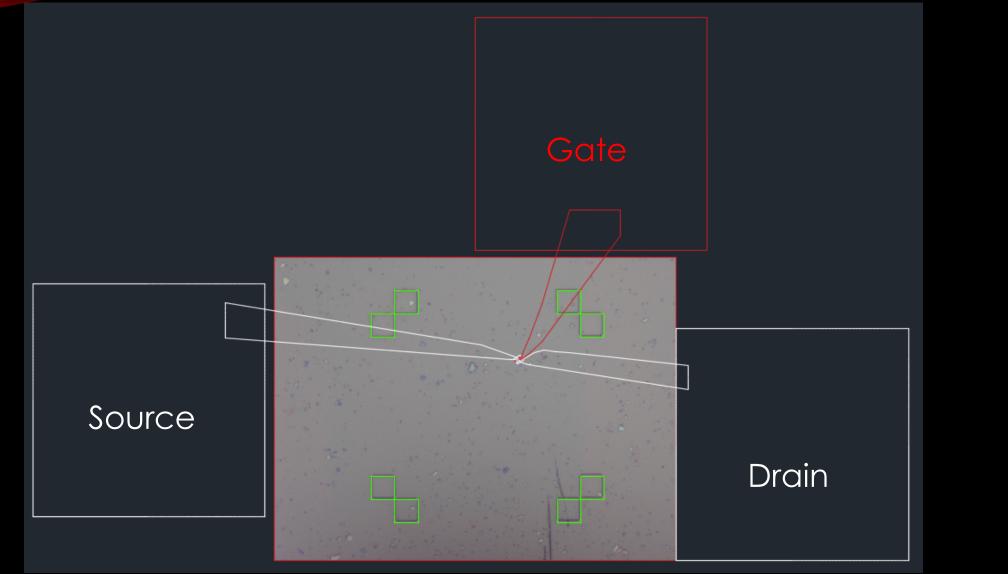




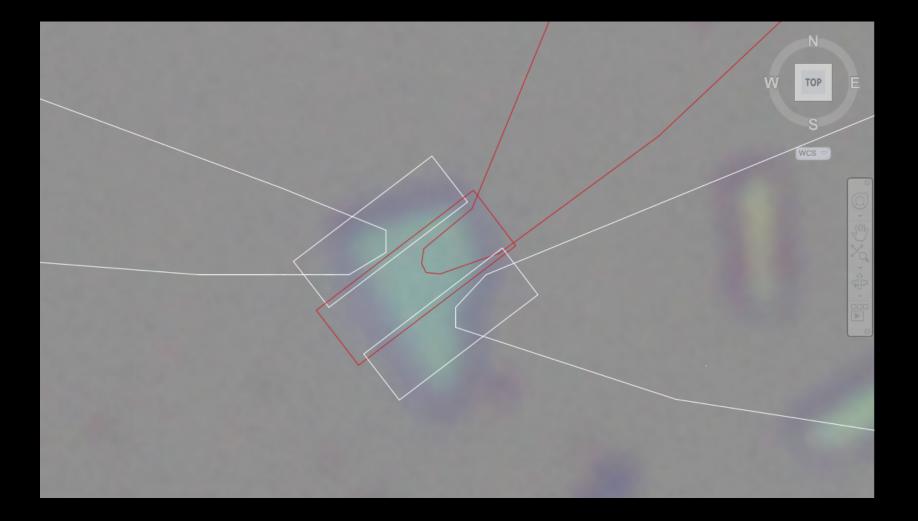


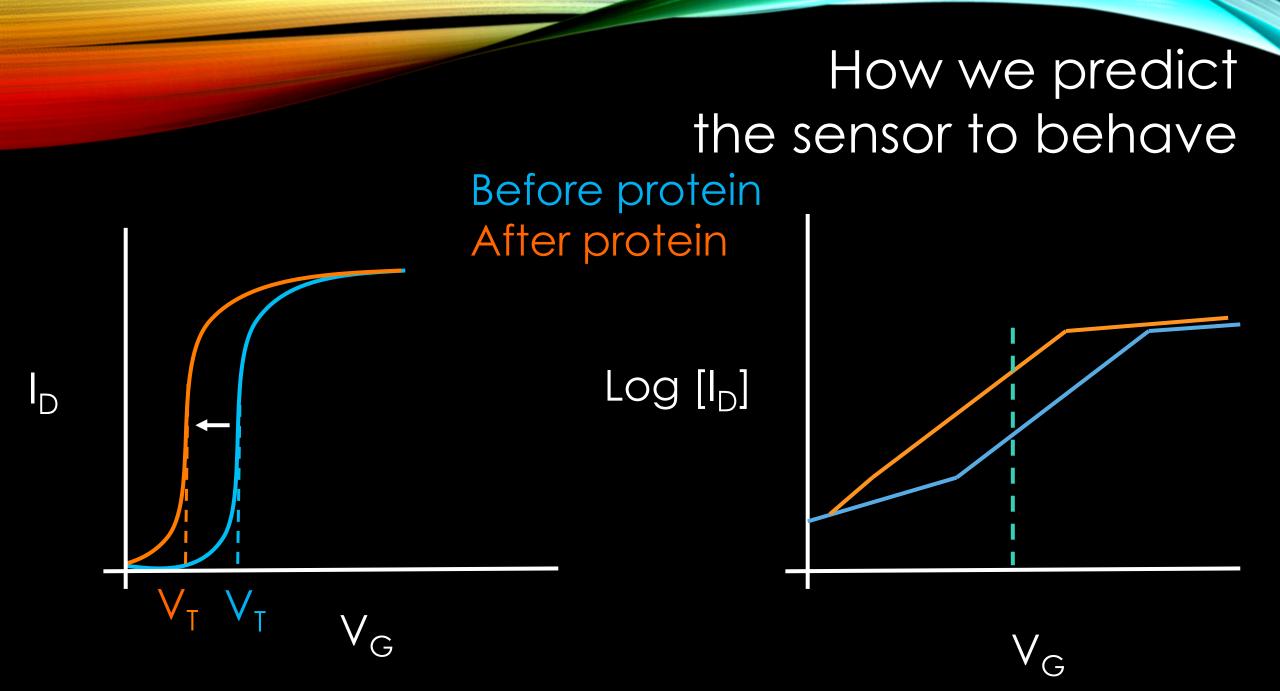
Length: ~2.365 µm Width:~3.751 µm Average Thickness: 17.959 nm

AutoCAD: Source, Gate, and Drain



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- Brought this project to a point where a working device is very nearly completed.
- When completed it will be a breakthrough in biomedical technology and diagnostic capability

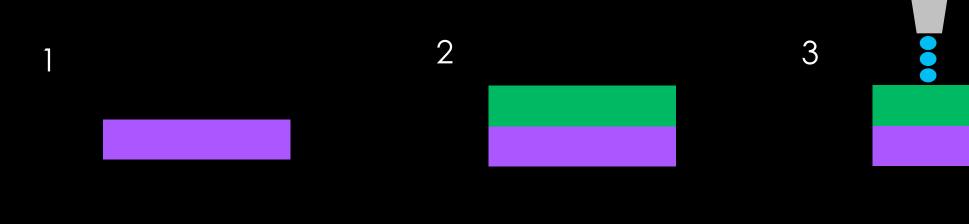
Acknowledgements

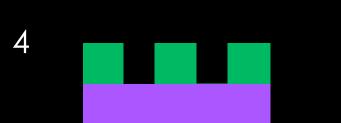
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- Dr. Joseph Kopanski
- NIST staff
- SPS staff

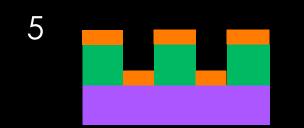


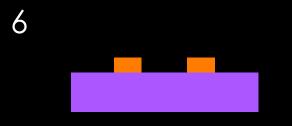


Future work: e-beam lithography









Future work

Probe Station

Wire Bonding to PC Board

Protein Sensing

